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(mems or "micro electromechanical" or microelectromechanical) and piezoelectric near electrode* and substrate near electrode*: 5 records

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(mems or "micro electromechanical" or microelectromechanical)



- | Title | Pub. Date | Int. Class | Applicant |
|---|------------|------------|---|
| 1. (WO 2006/014203) FUNCTIONAL MATERIAL FOR MICRO-MECHANICAL SYSTEMS | 09.02.2006 | B81B 3/00 | MASSACHUSETTS INSTITUTE OF TECHNOLOGY |
| A MEMS device includes a first material structure. A second material structure includes TiN. The second material structure is moveable relative to the first material structure. | | | |
| 2. (WO 2005/064701) ELECTRONIC DEVICE | 14.07.2005 | H01H 1/00 | KONINKLIJKE PHILIPS ELECTRONICS N.V. |
| The microelectromechanical system (MEMS) element (101) comprises a first electrode (31) that is present on a surface of a substrate (30) and a movable element (40), which overlies at least partially the first electrode (31) and comprises a piezoelectric actuator, which movable element (40) is movable towards and from the substrate (30) by application of an actuation voltage between a first and a second position, in which the first position is separated from the substrate (30) by a gap. The piezoelectric actuator comprises a piezoelectric layer (25) which opposite surfaces is provided with a second and a third electrode (21,22) respectively, said second electrode (21) facing the substrate (30) and said third electrode (22) forming an input e... | | | |
| 3. (WO 2005/001948) RADIAL BULK ANNULAR RESONATOR USING MEMS TECHNOLOGY | 06.01.2005 | H01L 41/00 | THE REGENTS OF THE UNIVERSITY OF CALIFORNIA |
| A MEMS resonator includes an annular resonator body defined by an inner radius and an outer radius, a first electrode positioned within the inner radius and spaced from the resonator body, and a second electrode positioned around the annular resonator body and spaced from the outer radius. The first electrode and the second electrode provide for capacitive drive of the resonator body and capacitive sense of the resonator body. Piezo-resistive sense and piezoelectric drive/sense techniques can also be utilized. The overall extent can be smaller than 1 cm ² in area and positioned on a supporting substrate by a plurality of anchors. The substrate can comprise an RF transceiver integrated circuit with the anchors connecting the drive electrode a... | | | |
| 4. (WO 2004/008635) MICROELECTROMECHANICAL APPARATUS AND METHODS FOR SURFACE ACOUSTIC WAVE SWITCHING | 22.01.2004 | H03H 9/02 | INTEL CORPORATION (a Delaware Corporation) (a Delaware Corporation) |
| Microelectromechanical system (MEMS) apparatus and methods for surface acoustic wave (SAW) switching are disclosed. The apparatus includes a piezoelectric substrate having spaced apart input and output SAW transducers. A MEMS switch is arranged between the input and output SAW transducers. The MEMS switch has a deformable member in electromagnetic communication with one or more actuation electrodes formed on or above the substrate. The deformable member is deformable to mechanically contact the substrate to deflect or absorb a SAW generated by the input SAW transducer. | | | |
| 5. (WO 2003/010878) MEMS ELEMENT HAVING PERPENDICULAR PORTION FORMED FROM SUBSTRATE | 06.02.2003 | B81B 3/00 | ONIX MICROSYSTEMS |
| Microelectromechanical systems (MEMS) elements, optical switches and fabrication methods are described. A MEMS element (101) comprises a crystalline moveable element moveably attached to a substrate for motion substantially perpendicular to a plane of the substrate. The moveable element includes a perpendicular portion (104) oriented substantially perpendicular to the substrate. In at least one position, a part of the perpendicular portion projects beyond a surface of the substrate. The perpendicular portion and substrate have substantially similar crystal structures. The perpendicular portion may be formed from the substrate. An array of such structures can implement an optical switch. | | | |

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32 results found in the Worldwide database for:

Mems or "micro electromechanical" or microelectromechanical in the title AND **piezoelectric and substrate** in the abstract

(Results are sorted by date of upload in database)

- 1 Piezoelectric RF MEMS device and method of fabricating the same**
Inventor: KIM JONG-SEOK (KR); SONG IN-SANG (KR); Applicant: SAMSUNG ELECTRONICS CO LTD
(+5)
EC: IPC: H01L41/053; H01L41/00
Publication info: US2007120445 - 2007-05-31
- 2 RF MEMS switch and method for fabricating the same**
Inventor: KIM JONG-SEOK (KR); KWON SANG-WOOK (KR); (+6) Applicant: SAMSUNG ELECTRONICS CO LTD
EC: H01P1/12D IPC: H01P1/10; H01P1/10
Publication info: US2007115081 - 2007-05-24
- 3 RF MEMS switch and fabrication method thereof**
Inventor: PARK JAE-YEONG (KR); LEE HEE-CHUL (KR) Applicant:
EC: IPC: H01P1/10; H01P1/10
Publication info: US2007109081 - 2007-05-17
- 4 RF MEMS switch and fabrication method thereof**
Inventor: PARK JAE-YEONG (KR); LEE HEE-CHUL (KR) Applicant:
EC: H01P1/12D IPC: H04R17/00; H01P1/12; H04R17/00 (+1)
Publication info: US2007094864 - 2007-05-03
- 5 MEMS switch actuated by the electrostatic force and piezoelectric force**
Inventor: KWON SANG-WOOK (KR); KIM JUN-O (KR); Applicant: SAMSUNG ELECTRONICS CO LTD
(+7)
EC: IPC: H01H51/22; H01H51/22
Publication info: US2007024403 - 2007-02-01
- 6 Semiconductor device using piezoelectric actuator formed by use of MEMS technique**
Inventor: IKEHASHI TAMIO (JP) Applicant: TOKYO SHIBAURA ELECTRIC CO
EC: IPC: H01L41/00; H01L41/00
Publication info: US2006290236 - 2006-12-28
- 7 METHOD FOR FABRICATING FBAR DEVICE USING MEMS METHOD**
Inventor: CHO SEONG RYEOL; JANG CHONG GYU; Applicant: ANTECHNOLOGY CO LTD
(+5)
EC: IPC: H03H3/02; H03H3/00; (IPC1-7): H03H3/02
Publication info: KR20040052851 - 2004-06-23
- 8 MEMS RF SWITCH HAVING STRUCTURE SERVING AS LEVER TRANSFERRING MOTION ON UPPER PORTION TO LOWER PORTION**
Inventor: CHO NAM GYU; LEE DAE SEONG; (+1) Applicant: KOREA ELECTRONICS TECHNOLOGY
EC: IPC: H01H59/00; H01H59/00; (IPC1-7): H01H59/00
Publication info: KR20040099808 - 2004-12-02
- 9 FLEXIBLE MEMS TRANSDUCER, METHOD FOR MANUFACTURING THE SAME AND FLEXIBLE MEMS WIRELESS MICROPHONE**
Inventor: LEE SUK HAN; NAM YUN U Applicant: SAMSUNG ELECTRONICS CO LTD
EC: B81B3/00K; B81B3/00M2D; (+2) IPC: H04R17/02; B81B3/00; H01L41/09 (+10)
Publication info: KR20040026756 - 2004-04-01
- 10 Semiconductor device formed by using MEMS technique**
Inventor: IKEHASHI TAMIO (JP) Applicant: TOKYO SHIBAURA ELECTRIC CO



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Query :

((relay or switch)) <AND> (((mems o

Query: ((relay or switch)) <AND> (((mems or "micro electromechanical" or microelectromechanical)) <in> abstract) <AND> (((piezoelectric and substrate and electrode*)) <in> claims)

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	type	L #	Hits	Search text	DBs	Stamp	s
1	BRS	L1	33	piezoelectric adj3 (relay or switch) same electrode same substrate	US- PGPUB ; USPAT ; USOCR ; FPRS; EPO; JPO; DERWE NT; IBM_T DB	2007/06/1 1 14:55	

and 30/348, 353, 352

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AND

electrode substrate

AND

AND

relay switch

OR

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AND

AND

electrode substrate

AND

AND

relay switch

OR

AND

Date of publication of application --- e.g. 19980401 - 19980405

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